

D. Thin Film Process Technology 분과

2020년 2월 14일(금), 09:00-10:30 / Room K (다이아몬드 I, 6층)

■ [FK1-D] Ferroelectric Materials

좌장: 김건환 박사 (화학연구원), 송봉근 교수 (홍익대학교)

FK1-D-1 09:00-09:15	A Study on the Ferroelectric Phase Formation in Doped Hafnia Thin Films based on Classical Nucleation Theory Min Hyuk Park ¹ , Young Hwan Lee ² , and Cheol Seong Hwang ² <i>¹School of Materials Science and Engineering, Pusan National University, ²Department of Materials Science and Engineering and Inter-University Semiconductor Research Center, College of Engineering, Seoul National University</i>
FK1-D-2 09:15-09:30	Numerical Comparisons in Switching Kinetics of Hf_{0.5}Zr_{0.5}O₂ Thin Films between the KAI and NLS Model Analyses Tae-Hyun Ryu, Dae-Hong Min, and Sung-Min Yoon <i>Department of Advanced Materials Engineering for Information and Electronics, Kyung Hee University</i>
FK1-D-3 09:30-09:45	Effects of High-pressure Hydrogen Annealing on the Ferroelectric Properties of W/Al:HfO₂/W Stacks Seungyeol Oh, In Keong Yoo, and Hyunsang Hwang <i>Department of Materials Science and Engineering, POSTECH</i>
FK1-D-4 09:45-10:00	Oxygen Partial Pressure Control during Sputtering Process on Ferroelectric Properties of Hf_{0.5}Zr_{0.5}O₂ and Device Operations of Memory Transistors Dae-Hong Min ¹ , Tae-Hyun Ryu ¹ , Seung Eon Moon ² , and Sung-Min Yoon ¹ <i>¹Department of Advanced Materials Engineering for Information and Electronics, Kyung Hee University, ²ETRI</i>
FK1-D-5 10:00-10:15	A Comparative Study on the Ferroelectric Performances in Atomic Layer Deposited Hf_{0.5}Zr_{0.5}O₂ Thin Films Using Tetrakis(ethylmethylamino) and Tetrakis(dimethylamino) Precursors Seung Dam Hyun ¹ , Baek Su Kim ¹ , Min Hyuk Park ² , and Cheol Seong Hwang ¹ <i>¹Department of Materials Science and Engineering and Inter-University Semiconductor Research Center, Seoul National University, ²School of Materials Science and Engineering, Pusan National University</i>
FK1-D-6 10:15-10:30	Synaptic Plasticity Modulation of Ferroelectric Field-Effect Synapse Transistor Using Al-doped HfO₂ Thin Film for Neuromorphic Applications So-Jung Yoon ¹ , Dae-Hong Min ¹ , Seung Eon Moon ² , and Sung-Min Yoon ¹ <i>¹Department of Advanced Materials Engineering for Information and Electronics, Kyung Hee University, ²ETRI</i>